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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Leonel R. Arana et al.

Serial No.: 10/807,836

Filed: March 24, 2004

For: Microfabricated Hot Wire
Vacuum Sensor

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Art Unit: 2813

Examiner: Heather Anne Doty

Docket: ITL.1133US
P19113

Assignee: Intel Corporation

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 20051108

Sir:

In response to the office action mailed November 16, 2005, please amend the above-referenced patent application as follows:

Date of Deposit: January 12, 2006

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden
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